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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)				Application Number	
				Filing Date	Herewith
				Applicant(s)	Chuan-Jen Wu
				Art Unit	
				Examiner Name	
SHEET	1	OF	2	Attorney Docket Number	24061.48 (TSMC2003-0059)

U. S. PATENT DOCUMENTS				
Examiner's Initials	Cite No	Document Number	Publication Date (MM-DD-YYYY)	Name of Patentee or Applicant of Cited Document
Rb	AA	5,050,088	09-17-1991	Buckler et al.
	AB	5,121,003	06-09-1992	Williams
	AC	5,283,896	02-01-1994	Temmyo et al.
	AD	5,513,132	04-30-1996	Williams
	AE	5,555,179	09-10-1996	Koyama et al.
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	AH	6,314,553	11-06-2001	Stevens et al.
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	AJ	6,421,808	07-16-2002	McGeer et al.
	AK	2003/0018512	01-23-2003	Dortmans

FOREIGN PATENT DOCUMENTS					
Examiner's Initials	Cite No	Foreign Patent Document (Country Code - Number - Kind)	Publication Date (MM-DD-YYYY)	Patentee or Applicant of Cited Document	Translation (Y/N)
Rb	AL	JP - 07-56886	03-03-1995	Noriaki et al.	N

OTHER PRIOR ART		
Examiner's Initials	Cite No	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue/number(s), publisher, city/country where published
Rb	AM	HYUN JOONG YOON et al., "Identification of Potential Deadlock Set in Semiconductor Track Systems", Proceedings of the 2001 IEEE Int'l Conference on Robotics & Automation, May 21-26, 2001, pgs. 1820-1825, Seoul, Korea
	AN	JIN YOUNG CHOI et al., "A Generalized Stochastic Petri net Model for Performance Analysis and Control of Capacited Re-entrant Lines", IEEE Transactions on R&A, 2003, 9 pgs., Volume XX.
	AO	ROBERT ESSER, et al., "Applying an Object-Oriented Petri Net Language to Heterogeneous Systems Design", 9 pgs.
	AP	MARK LaPEDUS, "Is e-diagnostics dead or alive in the industry?", Silicon Strategies, July 15, 2003, 3 pgs., Semiconductor Business News
	AQ	MU DER JENG et al., "Modeling, Qualitative Analysis, and Performance Evaluation of the Etching Area in an IC Wafer Fabrication System Using Petri Nets, IEEE Transaction on Semiconductor Manufacturing, Vol II, No. 3, 16 pgs., August, 1998.

Examiner Signature	<i>Renee Patal</i>	Date Considered	10/17/05
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

U. S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

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Attorney Docket Number	24061.48 (TSMC2003-0059)

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OTHER PRIOR ART		
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue number(s), publisher, city/country where published.
RL	AR	R. S. SRINIVASAN, "Modeling and Performance Analysis of Cluster Tools Using Petri Nets, IEEE Transactions on Semiconductor Manufacturing, Vol. II, No. 3, 10 pgs., August 1998
RL	AS	MENGCHU ZHOU et al., "Modeling, Analysis, Simulation, Scheduling, and Control of Semiconductor Manufacturing Systems: A Petri Net Approach", IEEE Transactions of Semiconductor Manufacturing, Vol. II, No. 3, 25 pgs., August 1998.

Examiner Signature	<i>Romeghy Patel</i>	Date Considered	<i>10/17/95</i>
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